



Docket No.: 9323.050.00-US
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

In-Kwon Jeong

Confirmation No.: 1220

Application No.: 09/917,344

Group Art Unit: 1763

Filed: July 27, 2001

Examiner: Macarthur, S.

For: CMP SYSTEM AND METHOD FOR
EFFICIENTLY PROCESSING
SEMICONDUCTOR WAFERS

Customer No.: 30827

AMENDMENT

Mail Stop RCE
Commissioner for Patents
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action dated September 28, 2005, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 19 of this paper.